#### (12) INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

# (19) World Intellectual Property Organization

International Bureau



# I (1881) BINNOUN II COMIN HON BENK BENK BINN IN NI BENE 1180) HON HON BURN BINN BINN BINN BINN BINN BINN BINN

# (43) International Publication Date 24 March 2005 (24.03.2005)

# **PCT**

# (10) International Publication Number WO 2005/027045 A1

(51) International Patent Classification7:

G06T 5/10

(21) International Application Number:

PCT/US2004/010789

(22) International Filing Date: 7 April 2004 (07.04.2004)

(25) Filing Language:

English

(26) Publication Language:

English

(30) Priority Data: 60/498,945

29 August 2003 (29.08.2003) US

(71) Applicant (for all designated States except US): THOM-SON LICENSING S.A. [FR/FR]; 46, Quai A. Le Gallo, F-92648 Boulogne (FR).

(72) Inventors; and

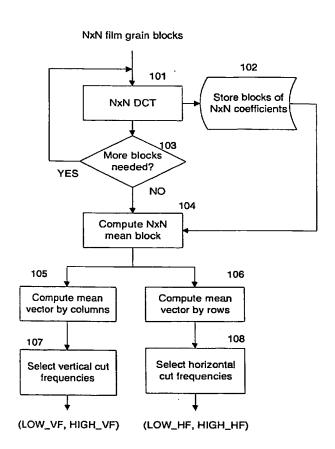
(75) Inventors/Applicants (for US only): GOMILA, Cristina

[ES/US]; 25C Chestnut Court, Princeton, NJ 08540 (US). LLACH, Joan [ES/US]; 25C Chestnut Court, Princeton, NJ 08540 (US).

- (74) Agents: TRIPOLI, Joseph, S. et al.; Thomson Licensing INC., Two Independence Way, Suite #200, Princeton, NJ 08540 (US).
- (81) Designated States (unless otherwise indicated, for every kind of national protection available): AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW.
- (84) Designated States (unless otherwise indicated, for every kind of regional protection available): ARIPO (BW, GH,

[Continued on next page]

(54) Title: METHOD AND APPARATUS FOR MODELING FILM GRAIN PATTERNS IN THE FREQUENCY DOMAIN



(57) Abstract: Film grain patterns can be modeled in the frequency domain by estimating the cut frequencies that define a 2D band-pass filter. The film grain parameters can be conveyed in accordance with the ITU-T H.264 | MPEG-4 AVC standard in an SEI message allowing film grain reinsertion at a decoder.

# WO 2005/027045 A1



GM, KE, LS, MW, MZ, SD, SL, SZ, TZ, UG, ZM, ZW), Eurasian (AM, AZ, BY, KG, KZ, MD, RU, TJ, TM), European (AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR), OAPI (BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG).

#### Published:

with international search report

For two-letter codes and other abbreviations, refer to the "Guidance Notes on Codes and Abbreviations" appearing at the beginning of each regular issue of the PCT Gazette.

-1-

# METHOD AND APPARATUS FOR MODELING FILM GRAIN PATTERNS IN THE FREQUENCY DOMAIN

## CROSS-REFERENCE TO RELATED APPLICATIONS

5

20

25

30

This application claims priority under 35 U.S.C. 119(e) to U.S. Provisional Patent Application Serial No 60/498,945, filed August 29, 2003, the teachings of which are incorporated herein.

# 10 TECHNICAL FIELD

This invention relates to a technique for modeling film grain patterns in the frequency domain.

## 15 BACKGROUND ART

Motion picture film typically contains signal-dependent noise, often referred to as film grain, resulting from the process of exposure and development of the photographic film. Such noise yields a characteristic quasi-random pattern or texture, caused by the physical granularity of the photographic emulsion. Alternatively, signal-dependent noise can occur as result of subsequent editing of the images. The grain pattern can be simulated for video compression purposes.

The ITU-T H.264 I MPEG-4 AVC video compression standard has accepted in its Fidelity Range Extensions Amendment the inclusion of a film grain SEI (Supplemental Enhancement Information) message. The film grain SEI message conveys a series of parameters allowing film grain simulation at the receiver. For the ITU-T H.264 I MPEG-4 AVC compression standard, parameters in the SEI message can be specified according to two different models: the auto-regressive model and the frequency-filtering model. Both models allow characterizing the film grain pattern (size and shape), intensity and color correlation through different sets of parameters for different intensity levels. In particular, the frequency-filtering model characterizes the film grain pattern by specifying a set of cut frequencies that

-2-

define a 2D band-pass filter in the frequency domain. Note that ITU-T H.264 IMPEG-4 AVC only standardizes the syntax necessary to transmit the cut frequencies but does not provide a method for computing them for a video sequence with film grain.

Thus, there exists a need for a technique allowing the automatic modeling of the film grain pattern in the frequency domain as specified by the frequency-filtering model in ITU-T H.264 | MPEG-4 AVC compression standard. Results for this technique could be used either for automatic film grain modeling applications or as the initialization step for a film grain assisted-modeling process.

#### BRIEF SUMMARY OF THE INVENTION

Briefly, in accordance with a preferred embodiment, there is provided a method for modeling (i.e., characterizing) film grain patterns in the frequency domain. The method comprises the steps of (1) transforming an set of homogeneous film grain samples received as an input to the process to the frequency domain, thereby yielding a set of transform coefficients having a particular pattern; (2) analyzing the pattern created by the transformed coefficients; and (3) estimating the cut frequencies of a 2D frequency filter that can effectively simulate the pattern of transform coefficients by filtering random noise. The cut frequencies established by this method can be conveyed in an SEI message in accordance with the ITU-T H.264 | MPEG-4 AVC standard allowing film grain simulation and reinsertion at a decoder.

## BRIEF DESCRIPTION OF THE DRAWINGS

FIGURE 1 depicts in flow chart form the steps of a method for characterizing film grain patterns in accordance with the present principles; and

FIGURE 2 depicts in flow chart form a variation of film grain characterization method of FIG. 1.

5

10

15

20

25

## **DETAILED DESCRIPTION**

5

10

15

FIGURE 1 depicts in flow chart form the steps of a method in accordance with present principles for modeling a film grain pattern in the frequency domain upon receipt of a series of film grain samples representing a homogeneous film grain pattern. As discussed in greater detail hereinafter, the method of the present principles parameterizes the pattern of the input samples by analyzing the size and shape of the structures forming the grain. Because grain can form differently depending on film exposure, homogeneous film grain samples are typically those associated with similar luminance values measured on the film image. Film grain samples at the input of the process could be any group (or groups) of neighboring pixels that retains information about the film grain size and shape. In the illustrated embodiment, we will assume for simplicity that the film grain samples are arranged in square blocks of NxN pixels with a particular transform implementation based on a DCT of squared blocks of NxN pixels, although other transforms, such as a Fast Fourier Transform work equally as well.

The method of the present principles assumes that modeling of the film grain present in  $I_{grain}[x, y, c]$  occurs in accordance with the relationship:

$$I_{grain}[x, y, c] = I_{without grain}[x, y, c] + G[x, y, c]$$
(1)

where G[x, y, c] represents the simulated grain at pixel coordinates (x, y) for color component c. G[x, y, c] is computed as:

$$G[x, y, c] = p * Q[x, y, c] + u * G[x, y, c-1]$$
 (2)

where the parameter p is the standard deviation of the random noise and the parameter u models the cross-color correlation among different color components. More particularly, the term Q[c] comprises a two-dimensional random field generated by filtering blocks b of N x M random values, which have been generated with a normalized Gaussian distribution N(0,1). In a particular embodiment, the band-pass filtering of blocks b can be performed in the frequency domain by the following three steps:

-4-.

Step 1: Transform

$$B = DCT_N \times M(b)$$

5 Step 2: Frequency filtering

```
for( y=0; y<N; y++)
for( x= 0; x<M; x++)
if ( (x < LOW_HF && y < LOW_VF) ||
x > HIGH_HF || y > HIGH_VF)
B[x, y] = 0;
```

where LOW\_HF and LOW\_VF are the low Horizontal and Vertical cut frequencies, respectively, and HIGH\_HF and HIGH\_VF are the high Horizontal and Vertical cut frequencies, respectively. The cut frequencies define the boundaries between preserved and filtered coefficients when a film grain image is mapped in the frequency domain and serve to characterize the size of the grain.

Step 3: Inverse Transform

20

25

15

$$b' = IDCT_N \times M(B)$$

Finally, Q[c] is formed by combining the filtered blocks b' into a composite image. Low pass filtering of the block transitions will reduce possible "blockiness." Although M and N could take any value, in practice squared blocks of 16x16, 8x8 or 4x4 pixels work best. Note also that other transforms, such as the Fast Fourier Transform (FFT), could replace the DCT process in Steps 1 and 3.

By these principles, modeling the film grain patterns is equivalent to extracting the cut
frequencies LOW\_HF, LOW\_VF, HIGH\_HF and HIGH\_VF that characterize the band-pass
filter in the frequency domain.

-5-.

The method of the present principles commences upon execution of step 101, in which each block of NxN pixels undergoes a Discrete Cosine Transform, with subsequent storage of the resulting arrays of NxN coefficients during step 102. During step 103, a check occurs to decide whether a need exists for more blocks with film grain samples in order to obtain more coefficients for storage. Ordinarily, all blocks of film grain samples available at the input undergo a transform. However, to reduce memory requirements or computational load, processing could stop after a certain number of blocks have undergone a transform. Following storage of a sufficient number of transformed blocks, step 104 occurs, whereupon a mean block ( $\mathbf{B}_{mean}$ ) is computed by averaging the coefficients from all the stored blocks. Assuming K as the number of stored blocks, the averaging process for the coefficient at position [x,y] can be formulated as follows:

$$\mathbf{B}_{mean}[x,y] = \frac{1}{K} \sum_{i=0}^{K-1} \mathbf{B}_{i}[x,y]$$
 (3)

Next, steps 105 and 106 occur typically in parallel. During step 105, a horizontal mean vector  $\mathbf{B}_{H}$  is computed by averaging the N frequency coefficients of each row of  $\mathbf{B}_{mean}$  in accordance with the relationship:

$$\mathbf{B}_{H}[y] = \frac{1}{N} \sum_{m=0}^{N-1} \mathbf{B}_{mean}[n, y]$$
 (4)

20

5

10

In a particular embodiment, it is possible to avoid the influence of the DC coefficient on the average of the first row with the relationship:

$$\mathbf{B}_{H}[0] = \frac{1}{N-1} \sum_{n=1}^{N-1} \mathbf{B}_{mean}[n,0]$$

25

During step 106, the vertical mean vector is computed by averaging the N frequency coefficients of each column of  $\mathbf{B}_{\text{mean}}$  in accordance with the relationship:

-6-

$$\mathbf{B}_{v}[x] = \frac{1}{N} \sum_{n=0}^{N-1} \mathbf{B}_{mean}[x, n]$$
 (5)

In a particular embodiment, it is possible to avoid the influence of the DC coefficient on the average of the first column with the relationship:

 $\mathbf{B}_{v}[0] = \frac{1}{N-1} \sum_{n=1}^{N-1} \mathbf{B}_{mean}[0, n]$ 

From the frequency vectors, selection of the horizontal and vertical cut frequencies occurs during steps 107 and 108, respectively, to estimate the film grain size. As seen in FIG. 1, steps 107 and 108 typically occur in parallel. Horizontal cut-frequency selection during step 107 occurs in the following manner. First, the components in the horizontal mean vector undergo low-pass filtering to avoid spurious peaks. In the illustrated embodiment, such low pass filtering of the horizontal mean vector occurs by convolving the mean vector with a filter of impulse response h[n] in accordance with the relationship.

15

10

5

$$\mathbf{B'}_{H}[n] = \sum_{i=1}^{n} \mathbf{B}_{H}[i]\mathbf{h}[n-i] = (\mathbf{B}_{H} * h)[n]$$
(6)

For example, a 3-tap linear filter with coefficients  $w_0$ ,  $w_1$ , and  $w_2$  could be applied to each coefficient in accordance with the relationship:

20

$$\mathbf{B'}_{H}[n] = w_0 \cdot \mathbf{B}_{H}[n-1] + w_1 \cdot \mathbf{B}_{H}[n] + w_2 \cdot \mathbf{B}_{H}[n+1], \quad 0 \le n \le N-1$$
 (7)

Observe that in order to apply the filtering on the edges of the mean vector  $\mathbf{B}$  it is necessary to pad the original mean vector so that the samples for n < 0 and n > N-1 are defined.

25

Next, the mean value of  $\mathbf{B'}_{H}$  is computed by averaging its components in accordance with the relationship:

-7-

$$\overline{B}'_{H} = \frac{1}{N} \sum_{n=0}^{N-1} \mathbf{B}'_{H} [n]$$
 (8)

Thereafter, the vector  $\mathbf{B'_H}$  is represented as a curve, and its intersection points with the average value  $\overline{B'_H}$  are computed. If a single intersection point is found, the index n of the closest component in  $\mathbf{B'_H}$  is chosen as the value of the horizontal high cut frequency; the horizontal low cut frequency is assumed to be 0. If two intersection points are found, the indexes of the closest components are found for each one. The lowest value will correspond to the low horizontal cut frequency whereas the highest value will correspond to the high horizontal cut frequency. If more than two intersection points are found, no spatial correlation is detected. The horizontal low cut frequency is assumed to be 0, and the horizontal high cut frequency is assumed to be N-1, indicating to the film grain simulation function that no frequency filtering is required to imitate the original grain.

5

10

15

20

25

The same procedure described for selecting the horizontal cut frequency occurs during step 108 to select the vertical cut frequency using the vertical frequency vector  $\mathbf{B}_{V}$ . At the completion of steps 107 and 108, the method of FIG. 1 yields four cut frequencies (LOW\_HF, HIGH\_HF, LOW\_VF, HIGH\_VF) that characterize both the size and the elongation of the grain. Elongated grain occurs when LOW\_HF  $\neq$  LOW\_VF and/or HIGH\_HF  $\neq$  HIGH\_VF.

FIGURE 2 illustrates an alternative grain modeling method, where it is possible to constrain the grain to circular shapes. This implies that the horizontal and vertical cut frequencies remain the same. The method of FIG. 2 contains many steps in common with the method of FIG. 1. Therefore, like reference numerals have been used in FIG. 2 as in FIG. 1 to describe like steps. The method of FIG. 2 differs from that of FIG. 1 in that, the vertical and horizontal frequency vectors ( $\mathbf{B}_H$  and  $\mathbf{B}_V$ ) are averaged during step 109 of FIG. 2 to create single frequency vector ( $\mathbf{B}$ ). Then, the same procedure is performed during steps 107 and 108 in FIG. 2 to estimate low and high cut frequencies as is performed during steps 107 and 108 of FIG. 1..

The foregoing describes a technique for modeling a film grain pattern in the frequency domain.

-8-

#### **CLAIMS**

1. A method for automatically modeling film grain patterns, comprising the steps of:

transforming a set of film grain samples to the frequency domain;

storing each set of coefficients resulting from such transform, the coefficients forming a pattern;

analyzing the pattern created by the transform coefficients; and

estimating the cut frequencies of a 2D band-pass filter that can effectively simulate the pattern of transform coefficients by filtering random noise in a frequency domain.

10

20

25

5

- 2. The method according to claim 1 further comprising the step of transmitting at least one cut frequency in a Supplemental Enhancement Information message.
- 3. The method according to claim 1 wherein the film grain samples are processed in blocks of NxN pixels.
  - 4. The method according to claim 3 wherein the step of analyzing the pattern created by the transform coefficients further comprises the steps of:

computing a mean block of NxN transform coefficients by averaging the transform coefficients from all the stored blocks;

defining horizontal and vertical mean vectors of N components each by averaging the mean block of NxN coefficients along rows and columns, respectively, of each transformed block;

representing the horizontal and vertical mean vectors as separate curves; and establishing horizontal and vertical cut frequencies from the curves represented by the horizontal and vertical mean vectors, respectively.

5. The method according to claim 4 further comprising the step of low pass filtering at least one mean vector.

-9-

- 6. The method according to claim 4 wherein the at least one cut frequency is established from an intersection point in the curve representing the mean vector.
- 7. The method according to claim 4 wherein each of a low and a high cut
   5 frequency is established from a first and second intersection points in the curve representing the mean vector.
  - 8. The method according to claim 3 wherein the step of analyzing the pattern created by the transform coefficients further comprises the steps of:

computing a mean block of NxN transform coefficients by averaging the transform coefficients from all the stored blocks;

defining horizontal and vertical mean vectors of N components each by averaging the mean block of NxN transform coefficients along rows and columns, respectively, of each transformed block;

averaging the horizontal and vertical mean vectors into a single mean vector; representing the mean vectors as a curve; and

establishing horizontal and vertical cut frequencies from the curve represented by the mean vector.

- 9. The method according to claim 8 further comprising the step of low pass filtering the mean vector.
  - 10. The method according to claim 8 wherein at least one cut frequency is established from an intersection point in the curve representing the mean vector.
  - 11. The method according to claim 8 wherein each of a low and a high cut frequency is established from a first and second intersection points in the curve representing the mean vector.

25

10

15

12. A method for automatically modeling film grain patterns, comprising the steps of:

receiving a set of film grain samples

5

10

performing a transform on the set of film grain samples to the frequency domain storing each set of coefficients resulting from such transform, the coefficients forming a pattern;

analyzing the pattern created by the transform coefficients; and estimating the cut frequencies of a 2D band-pass filter that can effectively simulate the pattern of transform coefficients by filtering random noise in a frequency domain.

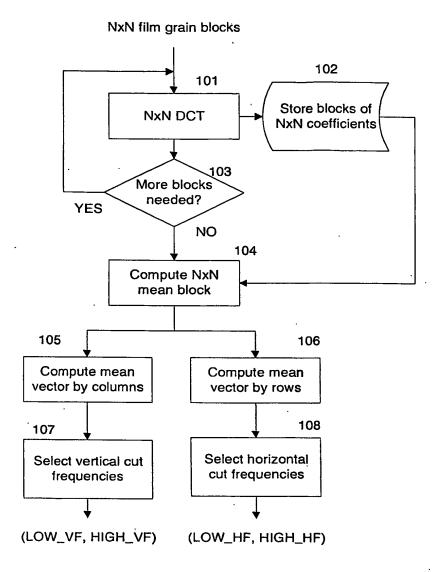


FIGURE 1

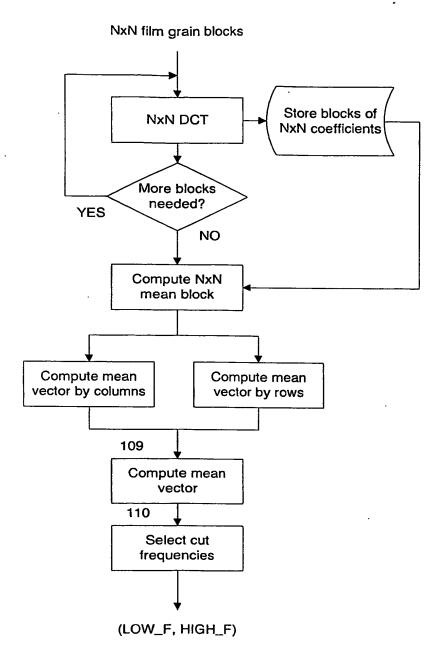


FIGURE 2

# INTERNATIONAL SEARCH REPORT

mational Application No ST/US2004/010789

A. CLASSIFICATION OF SUBJECT MATTER IPC 7 G06T5/10

According to International Patent Classification (IPC) or to both national classification and IPC

## B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

IPC 7 GO6T

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

EPO-Internal, WPI Data, IBM-TDB, INSPEC, COMPENDEX, PAJ

ategory °	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
1	US 5 641 596 A (COK DAVID R ET AL) 24 June 1997 (1997-06-24) abstract column 1, line 38 - column 2, line 60 column 6, line 19 - line 67 column 7, line 31 - line 36	1-12
<b>,</b>	US 4 935 816 A (FABER ROBERT A) 19 June 1990 (1990-06-19) abstract column 3, line 17 - line 19 column 3, line 62 - column 4, line 2 column 7, line 11 - line 35	1-12
	- <b>/</b>	

χ Further documents are listed in the continuation of box C.	χ Patent family members are listed in annex.	
<ul> <li>Special categories of cited documents:</li> <li>"A" document defining the general state of the art which is not considered to be of particular relevance</li> <li>"E" earlier document but published on or after the international filing date</li> <li>"L" document which may throw doubts on priority claim(s) or which is cited to establish the publication date of another citation or other special reason (as specified)</li> <li>"O" document referring to an oral disclosure, use, exhibition or other means</li> <li>"P" document published prior to the international filing date but later than the priority date claimed</li> </ul>	<ul> <li>*T* tater document published after the International filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention</li> <li>*X* document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone</li> <li>*Y* document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art.</li> <li>*&amp;* document member of the same patent family</li> </ul>	
Date of the actual completion of the international search  · 11 August 2004	Date of malling of the international search report  24/08/2004	
Name and mailing address of the ISA  European Patent Office, P.B. 5818 Patentlaan 2  NL – 2280 HV Rijswijk  Tel. (+31-70) 340-2040, Tx. 31 651 epo nl,  Fax: (+31-70) 340-3016	Authorized officer  Eckert, L	

# INTERNATIONAL SEARCH REPORT

T/US2004/010789

	citation of document with indication, where appropriate of the relevant passages	Relevant to claim No	
Category °	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.	
•	US 6 269 180 B1 (SEVIGNY BENOIT) 31 July 2001 (2001-07-31) abstract column 1, line 32 - line 47. column 3, line 54 - line 57 column 4, line 55 - line 56 column 5, line 36 - column 6, line 17	1-12	

LEISTA HOURAL OLANOH INCLUDE

Information on patent family members

CT/US2004/010789

Patent document cited in search report		Publication date		Patent family member(s)	Publication date
US 5641596	Α	24-06-1997.	NONE		· · · · · · · · · · · · · · · · · · ·
US 4935816	Α .	19-06-1990	NONE		
US 6269180	B1	31-07-2001	CA GB	2201682 A1 2312124 A ,B	12-10-1997 15-10-1997

Form PCT/ISA/210 (patent family annex) (January 2004)